

Docket No. 209284US99



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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Zhiyi YU, et al.

SERIAL NO: 09/842,734

GAU: 2811

FILED: April 26, 2001

EXAMINER: HU, SHOUXIANG

FOR: STRUCTURE AND METHOD FOR FABRICATING SEMICONDUCTOR STRUCTURES AND DEVICES USING BINARY METAL OXIDE LAYERS

EXPRESS ABANDONMENT UNDER 37 CFR 1.138

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

☒ **Express Abandonment**

Applicant's Representative requests that the above-identified application be expressly abandoned as of the filing date of this paper.

☐ **Express Abandonment in Favor of a Continuing Application**

Applicant's Representative requests that the above-identified application be expressly abandoned as of the filing date accorded the continuing application filed herewith.

☐ **Petition for Express Abandonment to Avoid Publication under 37 C.F.R. 1.138(c)**

Applicant's Representative hereby petitions to expressly abandon the above-identified application under 37 CFR 1.138(c) to avoid publication.

The required petition fee under 37 CFR 1.17(h) of \$130.00 is enclosed herewith by credit card payment form and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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Respectfully submitted,

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